

PATENT ABSTRACTS OF JAPAN

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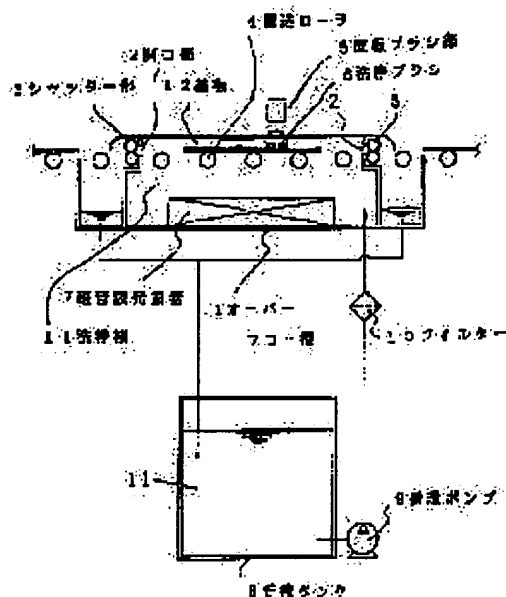
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(54) SUBSTRATE CLEANING DEVICE

(57)Abstract:

PURPOSE: To prevent the deterioration with age due to the pollution of a brush itself by moving a substrate between the opening parts of an overflow tank with the substrate in a clearing solvent, applying an ultrasonic wave to the clearing solvent to clean the substrate in the clearing solvent by brushing.

CONSTITUTION: A substrate 12 is moved in a right direction along a pass line by a transfer roller 4 and dipped into the liquid of an overflow tank 1 by way of a shutter part 3 and an opening part 2, and the surface of a substrate 12 is cleaned by scrubbing with a cleaning brush 6 of a rotary brush part 5. The rear surface of the substrate 12 and the cleaning brush 6 are cleaned with the effect of an ultrasonic wave from an ultrasonic wave oscillator 7. A cleaning solvent overflowed from an overflow tank 1 is collected into a storage tank 8. Thereby, the lowering of cleaning ability due to the pollution of the cleaning brush itself may be prevented.



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